

Sustainable Synthesis of Hollow Cu-loaded Poly(*m*-phenylenediamine) particles and Their Application for Arsenic Removal

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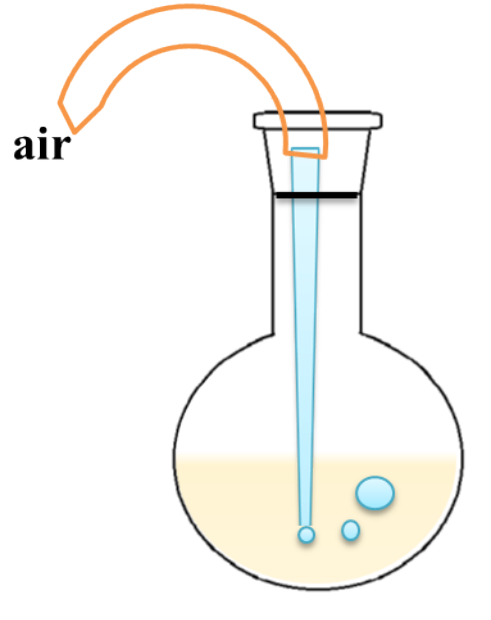
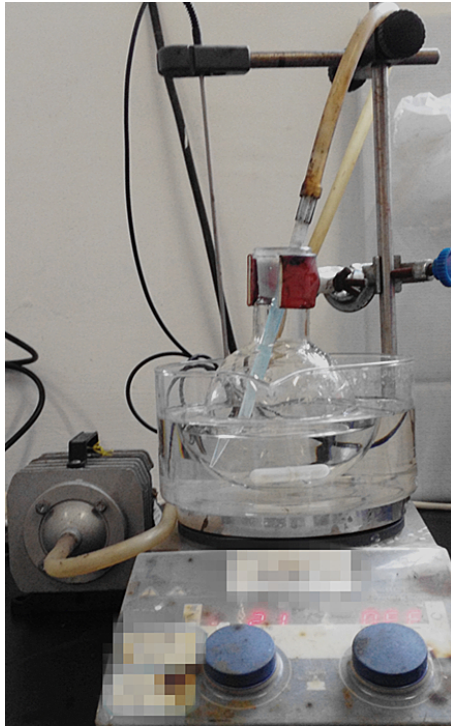
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Electronic Supplementary Information

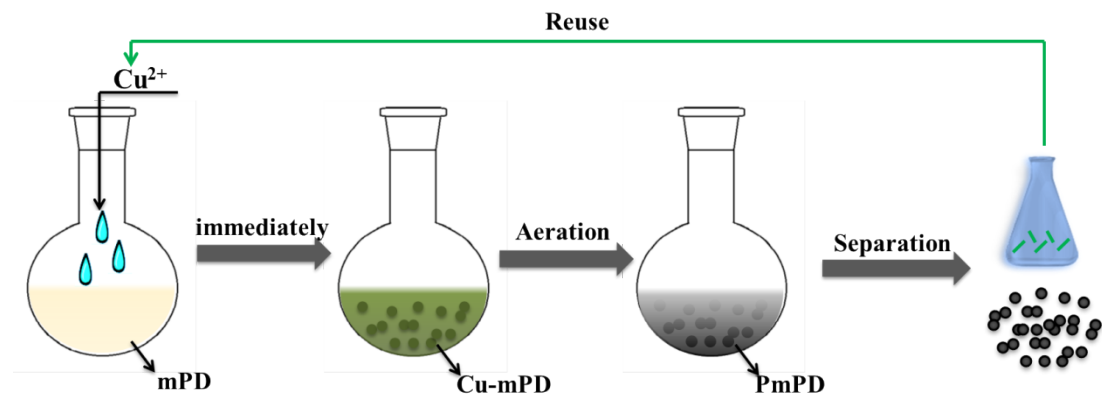
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ESI-1 Equipment



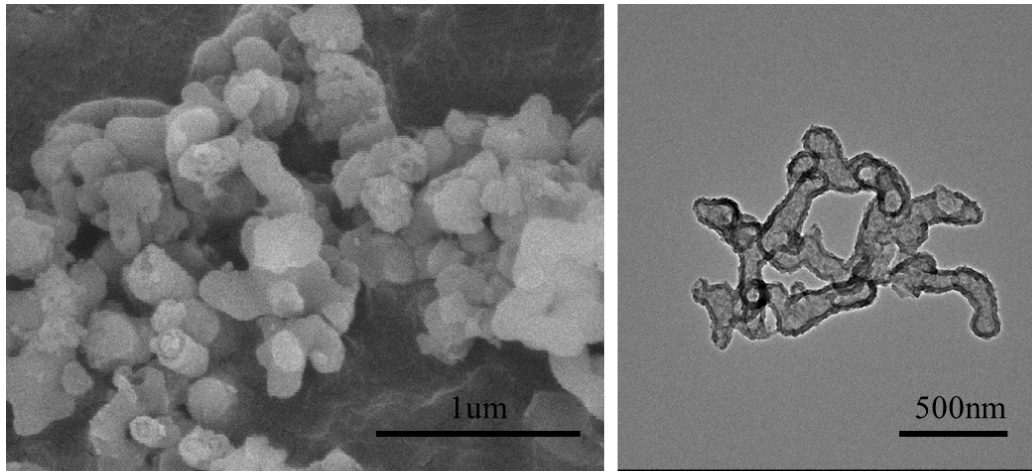
ESI-2 Synthesis sketch map



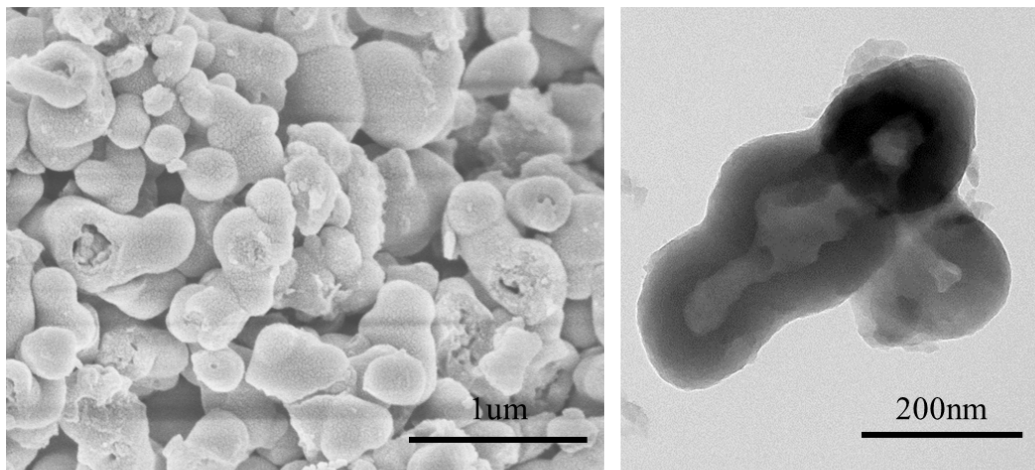
ESI-3 Total TOC and Cu amounts in filtrates after polymerization

PmPD-name	TOC in filtrate (mg L ⁻¹)	Total Cu in filtrate (mg)
<i>Cu1:1</i>	8.7±0.4	864±44
<i>Cu1:0.5</i>	9.65±0.6	445±38
<i>Cu1:0.25</i>	122.5±4	65±2

ESI-4 SEM and TEM images of PmPD-Cu1:1 in different time.

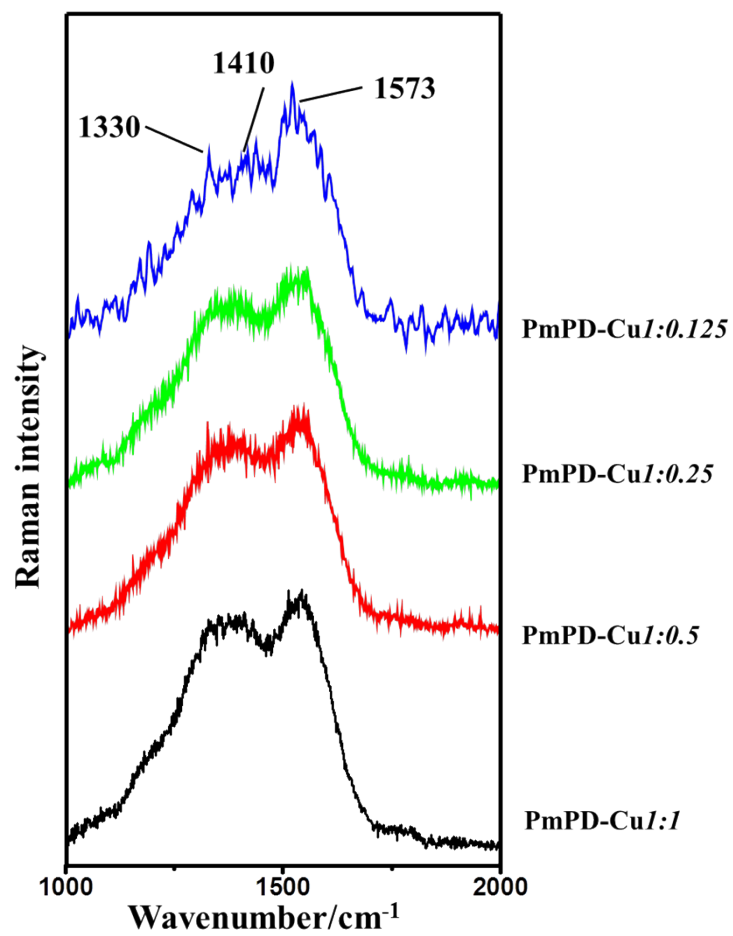


(a) PmPD-Cu1:1-before air introduction



(b) PmPD-Cu1:1 -after reaction for 6h

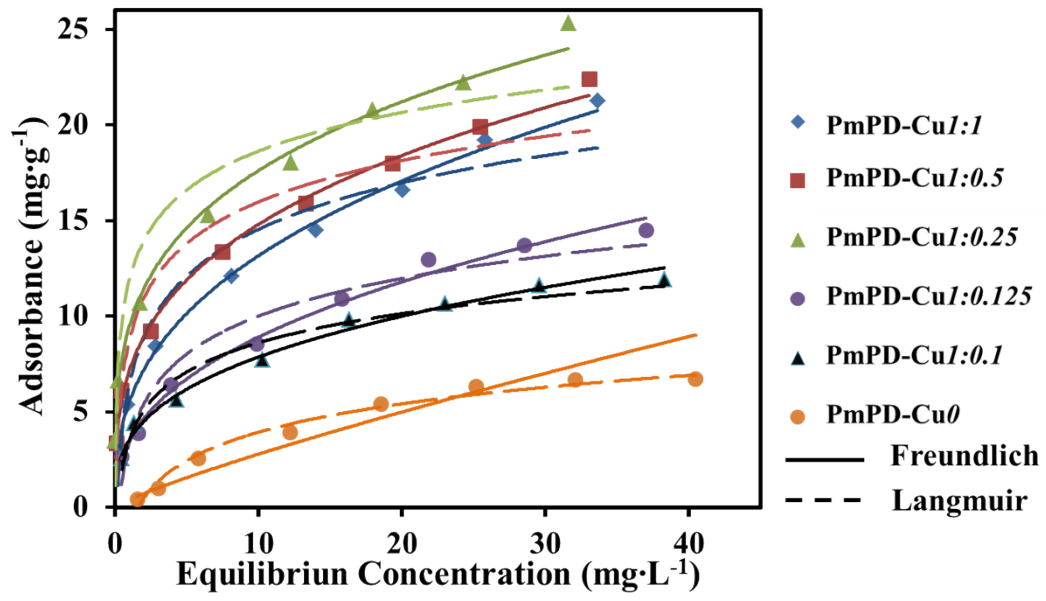
ESI-5 Raman spectra of PmPD particles.



ESI-6 Parameters of Langmuir and Freundlich models simulated by liner fit for the adsorption of arsenic on PmPD particles.

PmPD-name	Langmuir model		
	K_L	$Q_m(\text{mg}\cdot\text{g}^{-1})$	R^2
<i>CuI:1</i>	0.0295±0.0004	24.51±0.12	0.9784±0.0032
<i>CuI:0.5</i>	0.0382±0.0013	24.60±0.33	0.9845±0.0004
<i>CuI:0.25</i>	0.0448±0.0039	28.13±0.12	0.9793±0.0051
<i>CuI:0.125</i>	0.0298±0.0005	16.63±0.10	0.9853±0.0071
<i>CuI:0.1</i>	0.0399±0.0021	13.12±0.19	0.9897±0.0045
<i>Cu0</i>	0.0089±0.0011	11.24±0.69	0.9913±0.0001

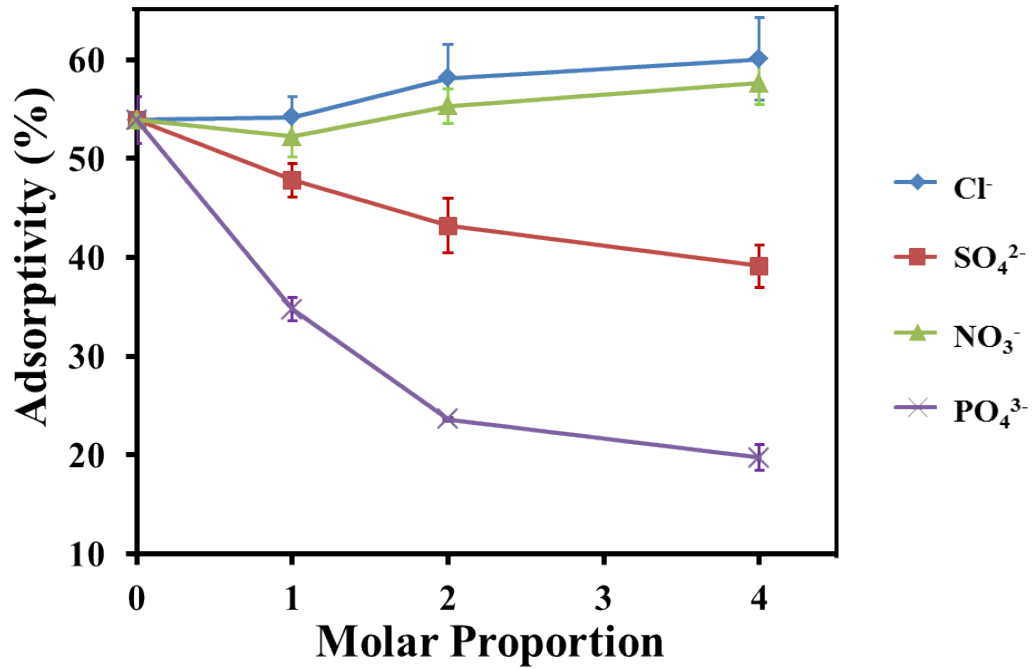
PmPD-name	Freundlich model		
	K_F	1/n	R^2
<i>CuI:1</i>	3.0191 ± 0.0719	0.3613 ± 0.0068	0.9962 ± 0.0008
<i>CuI:0.5</i>	3.8971 ± 0.3005	0.3216 ± 0.0122	0.9956 ± 0.0015
<i>CuI:0.25</i>	5.9635 ± 0.0027	0.2699 ± 0.0002	0.9951 ± 0.0026
<i>CuI:0.125</i>	2.0266 ± 0.0487	0.4009 ± 0.0119	0.9896 ± 0.0051
<i>CuI:0.1</i>	1.7481 ± 0.0569	0.3334 ± 0.0090	0.9888 ± 0.0041
<i>Cu0</i>	0.1030 ± 0.0162	0.8142 ± 0.0420	0.9563 ± 0.0048



ESI-7 Kinetic parameters of Pseudo-first and -second models for the adsorption of arsenic on PmPD-Cu1:0.25.

PmPD-name		Cu1:0.25
	$Q_{e,exp}$	6.55 ± 0.19
Pseudo-first-order model	$k(\text{min}^{-1})$	0.00058 ± 0.00012
	$Q_{e,cal} (\text{mg}\cdot\text{g}^{-1})$	1.247 ± 0.029
	R^2	0.8662 ± 0.1037
Pseudo-second-order model	$h(\text{min}^{-1})$	2.522 ± 0.538
	$Q_{e,cal} (\text{mg}\cdot\text{g}^{-1})$	6.081 ± 0.0278
	R^2	0.99996 ± 0.00003

ESI-8 Effect of coexisting ions on AsO_4^{3-} adsorption with PmPD-Cu1:0.25.



Molar Proportion is the molar proportion of competing anions to AsO_4^{3-} (from 1:1 to 4:1).